



648.43518X00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: TETSUKA et al

EXPEDITED PROCEDURE

Serial No.: 10/784,275

Filed: February 24, 2004

For: Plasma Processing Apparatus And Plasma Processing Method

Art Unit: 1763

Examiner: R. Zervigon

AMENDMENT AFTER FINAL ACTION

Mail Stop: Box AF Amendment (No Fee)
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

January 16, 2007

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application, in response to the Office Action dated October 13, 2006. The amendments are listed below and set forth on the following pages.

Amendments to the Claims; and

Remarks are included following the amendments.